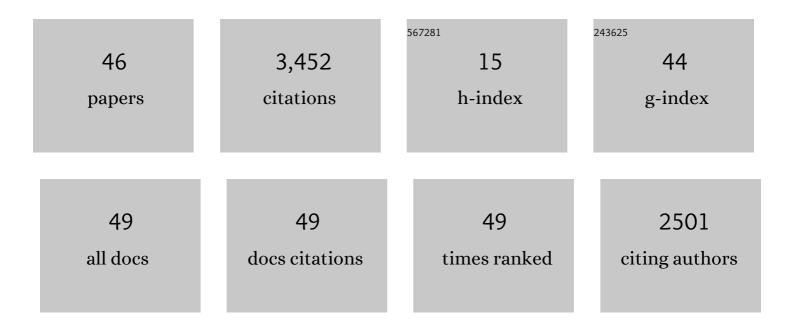
Hiroshi Amano

List of Publications by Year in descending order

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ΗΙΡΟΣΗΙ ΔΜΑΝΟ

| # | Article | IF | CITATIONS |
|----|---|-----|-----------|
| 1 | Ohmic Contact to <i>p</i> -Type GaN Enabled by Post-Growth Diffusion of Magnesium. IEEE Electron Device Letters, 2022, 43, 150-153. | 3.9 | 12 |
| 2 | Defect characterization of $\{101 \hat{A}^-3\}$ GaN by electron microscopy. Journal of Applied Physics, 2022, 131, . | 2.5 | 5 |
| 3 | Interplay of sidewall damage and light extraction efficiency of micro-LEDs. Optics Letters, 2022, 47, 2250. | 3.3 | 15 |
| 4 | Inhomogeneous Barrier Height Characteristics of n-Type AlInP for Red AlGaInP-Based Light-Emitting Diodes. ECS Journal of Solid State Science and Technology, 2022, 11, 035007. | 1.8 | 0 |
| 5 | Improved performance of deep ultraviolet AlGaN-based light-emitting diode by reducing contact resistance of Al-based reflector. Journal of Alloys and Compounds, 2022, 910, 164895. | 5.5 | 2 |
| 6 | Laser slice thinning of GaN-on-GaN high electron mobility transistors. Scientific Reports, 2022, 12, 7363. | 3.3 | 4 |
| 7 | The stability of graphene and boron nitride for III-nitride epitaxy and post-growth exfoliation. Chemical Science, 2021, 12, 7713-7719. | 7.4 | 24 |
| 8 | Generalized Frequency Dependent Small Signal Model for High Frequency Analysis of AlGaN/GaN MOS-HEMTs. IEEE Journal of the Electron Devices Society, 2021, 9, 570-581. | 2.1 | 6 |
| 9 | Development of Pulsed TEM Equipped with Nitride Semiconductor Photocathode for High-Speed Observation and Material Nanofabrication. Quantum Beam Science, 2021, 5, 5. | 1.2 | 5 |
| 10 | Experimental demonstration of GaN IMPATT diode at X-band. Applied Physics Express, 2021, 14, 046501. | 2.4 | 10 |
| 11 | Microâ€Light Emitting Diode: From Chips to Applications. Laser and Photonics Reviews, 2021, 15, 2000133. | 8.7 | 108 |
| 12 | Non-polar true-lateral GaN power diodes on foreign substrates. Applied Physics Letters, 2021, 118, . | 3.3 | 8 |
| 13 | Gallium nitride wafer slicing by a sub-nanosecond laser: effect of pulse energy and laser shot spacing. Applied Physics A: Materials Science and Processing, 2021, 127, 1. | 2.3 | 3 |
| 14 | High-Gain Gated Lateral Power Bipolar Junction Transistor. IEEE Electron Device Letters, 2021, 42, 1370-1373. | 3.9 | 2 |
| 15 | Smart-cut-like laser slicing of GaN substrate using its own nitrogen. Scientific Reports, 2021, 11, 17949. | 3.3 | 7 |
| 16 | Etching-induced damage in heavily Mg-doped p-type GaN and its suppression by low-bias-power inductively coupled plasma-reactive ion etching. Japanese Journal of Applied Physics, 2021, 60, SBBD03. | 1.5 | 12 |
| 17 | Optical properties of neodymium ions in nanoscale regions of gallium nitride: erratum. Optical Materials Express, 2021, 11, 524. | 3.0 | 0 |
| 18 | Modified Small Signal Circuit of AlGaN/GaN MOS-HEMTs Using Rational Functions. IEEE Transactions on Electron Devices, 2021, 68, 6059-6064. | 3.0 | 3 |

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| # | Article | IF | CITATIONS |
|----|---|--------------------------|--------------------------|
| 19 | Ohmic contact on low-doping-density p-type GaN with nitrogen-annealed Mg. Applied Physics Letters, 2021, 119, . | 3.3 | 11 |
| 20 | Space charge profile study of AlGaN-based p-type distributed polarization doped claddings without impurity doping for UV-C laser diodes. Applied Physics Letters, 2020, 117, | 3.3 10 Tf 50 6 | 26 87 Td (xmln |
| 21 | | 3.8 | 2 |
| 22 | Damage-free plasma etching to enhance performance of AlGaInP-based micro-light emitting diode. IEEE Photonics Technology Letters, 2020, , 1-1. | 2.5 | 4 |
| 23 | Surface passivation of light emitting diodes: From nano-size to conventional mesa-etched devices. Surfaces and Interfaces, 2020, 21, 100765. | 3.0 | 11 |
| 24 | Improving the Leakage Characteristics and Efficiency of GaN-based Micro-Light-Emitting Diode with Optimized Passivation. ECS Journal of Solid State Science and Technology, 2020, 9, 055001. | 1.8 | 35 |
| 25 | Improved Light Output of AlGaInP-Based Micro-Light Emitting Diode Using Distributed Bragg Reflector. IEEE Photonics Technology Letters, 2020, 32, 438-441. | 2.5 | 11 |
| 26 | On-wafer fabrication of etched-mirror UV-C laser diodes with the ALD-deposited DBR. Applied Physics Letters, 2020, 116, . | 3.3 | 42 |
| 27 | Photoluminescence properties of implanted Praseodymium into Gallium Nitride at elevated temperatures. Nuclear Instruments & Methods in Physics Research B, 2020, 479, 7-12. | 1.4 | 2 |
| 28 | Recovery of quantum efficiency on Cs/O-activated GaN and GaAs photocathodes by thermal annealing in vacuum. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2020, 38, . | 1.2 | 5 |
| 29 | Optical properties of neodymium ions in nanoscale regions of gallium nitride. Optical Materials Express, 2020, 10, 2614. | 3.0 | 11 |
| 30 | Vertical GaN-on-GaN Schottky Diodes as α-Particle Radiation Sensors. Micromachines, 2020, 11, 519. | 2.9 | 17 |
| 31 | Change of high-voltage conduction mechanism in vertical GaN–on–GaN Schottky diodes at elevated temperatures. Applied Physics Express, 2020, 13, 074001. | 2.4 | 3 |
| 32 | Combined effects of V pits and chip size on the electrical and optical properties of green InGaN-based light-emitting diodes. Journal of Alloys and Compounds, 2019, 796, 146-152. | 5.5 | 28 |
| 33 | The emergence and prospects of deep-ultraviolet light-emitting diode technologies. Nature Photonics, 2019, 13, 233-244. | 31.4 | 800 |
| 34 | Fully Ion Implanted Normally-Off GaN DMOSFETs with ALD-Al2O3 Gate Dielectrics. Materials, 2019, 12, 689. | 2.9 | 21 |
| 35 | Low Voltage High-Energy α-Particle Detectors by GaN-on-GaN Schottky Diodes with Record-High Charge Collection Efficiency. Sensors, 2019, 19, 5107. | 3.8 | 10 |
| 36 | Light output performance of red AlGaInP-based light emitting diodes with different chip geometries and structures. Optics Express, 2018, 26, 11194. | 3.4 | 135 |

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| # | Article | IF | CITATIONS |
|----|--|-----|-----------|
| 37 | DFT modeling of carbon incorporation in GaN(0001) and GaN(0001Â ⁻) metalorganic vapor phase epitaxy. Applied Physics Letters, 2017, 111, . | 3.3 | 19 |
| 38 | Study of radiation detection properties of GaN pn diode. Japanese Journal of Applied Physics, 2016, 55, 05FJ02. | 1.5 | 14 |
| 39 | Growth of GaN on sapphire via lowâ€ŧemperature deposited buffer layer and realization of pâ€ŧype GaN by Mg doping followed by lowâ€energy electron beam irradiation (Nobel Lecture). Annalen Der Physik, 2015, 527, 327-333. | 2.4 | 16 |
| 40 | Strain relaxation in thick (\$1{ar {1}}01\$) InGaN grown on GaN/Si substrate. Physica Status Solidi (B): Basic Research, 2012, 249, 468-471. | 1.5 | 3 |
| 41 | Growth of InGaN nanowires on a (111)Si substrate by RFâ€MBE. Physica Status Solidi C: Current Topics in Solid State Physics, 2012, 9, 646-649. | 0.8 | 21 |
| 42 | Effect of lateral vapor phase diffusion during the selective growth of InGaN/GaN MQW on semipolar and nonpolar GaN stripes. Physica Status Solidi (A) Applications and Materials Science, 2011, 208, 1175-1178. | 1.8 | 7 |
| 43 | Optical properties of (1â€101) InGaN/GaN MQW stripe laser structure on Si substrate. Physica Status Solidi C: Current Topics in Solid State Physics, 2011, 8, 2160-2162. | 0.8 | 8 |
| 44 | Selective MOVPE growth of InGaN/GaN MQW on microfacet GaN stripes. Physica Status Solidi C: Current Topics in Solid State Physics, 2011, 8, 2038-2040. | 0.8 | 1 |
| 45 | Growth and Luminescence Properties of Mgâ€Doped GaN Prepared by MOVPE. Journal of the Electrochemical Society, 1990, 137, 1639-1641. | 2.9 | 209 |
| 46 | P-Type Conduction in Mg-Doped GaN Treated with Low-Energy Electron Beam Irradiation (LEEBI). Japanese Journal of Applied Physics, 1989, 28, L2112-L2114. | 1.5 | 1,754 |